The MX61L/ MX61, 300 mm/ 200 mm semiconductor inspection microscope provides exceptional image resolution and clarity through observation methods such as bright field, darkfield, differential interference contrast (DIC), fluorescence and infrared.

Optical System			UIS2 Optical System (Infinity-corrected)
Microscope Frame	Observation Method		BF/DF/DIC/KPO*/FL
	Reflected/Transmitted Illuminator		Reflected/Transmitted Microscope Frame All-in-one (BF, DF + 1 Option)
	Illumination System	Reflected Light	100 W Halogen/100 W Mercury/75 W Xenon
		Transmitted Light	Fiber Light Guide
	Focus	Motorized/Manual	Manual
		Stroke	32 mm
		Resolution/Fine Adjustment Sensitivity	Fine Stroke per Rotation 0.1 mm
		Maximum Specimen Height	30 mm

	Revolving Nosepiece	Motorized Type	Sextuple for BF/DIC Quintuple for BF/DF/DIC Centerable Quintuple for BF/DF/DIC Sextuple for BF/DF/DIC	
		Manual Type	-	
Stage	Stroke		14x12 inch Right Handle Stage: 356(X)x305(Y)mm (Transmitted Light Range 356x284 mm)	8x8 inch Right Handle Stage: 210(X)x210(Y)mm (Transmitted Light Range 189x189 mm) 6x6 inch Right Handle Stage: 158(X)x158(Y)mm
Observation Tube	Widefield (Field Number 22)	Inverted Image	Binocular/Trinocular Observation Tube	
		Erect Image	Trinocular Observation Tube	
	Super Wide Field (Field Number 26.5)	Inverted Image	Trinocular Observation Tube	
		Erect Image	Tilting Trinocular Observation Tube	
Option Unit			IR Unit/Motorized Stage/Wafer Loader	
Dimensions			710(W)x843(D)x507(H)mm (in Standard Combination)	509(W)x843(D)x507(H)mm (in Standard Combination)
Weight			51 kg (in Standard Combination)	40 kg (in Standard Combination)
Remark			*Simple Polarized Light Observation